SUMMARY

[0003A] In accordance with a first aspect, there is provided a fluid ejection device, comprising:

a fluid supply chamber to store fluid;

a plurality of ejection chambers including nozzles and corresponding ejection members to selectively eject the fluid through the respective nozzles;

a channel to establish fluid communication between the fluid supply chamber and the ejection members;

a temperature adjustment module to establish at least one temperature of the fluid of the fluid ejection device; and

a sensor unit having a sensor plate, the sensor unit to detect at least one impedance in the fluid corresponding to the at least one temperature

[0003B] In accordance with a second aspect, there is provided a fluid ejection device, comprising:

a fluid supply chamber to store fluid;

a plurality of ejection chambers including nozzles and corresponding ejection members to selectively eject the fluid through the respective nozzles;

a channel to establish fluid communication between the fluid supply chamber and the ejection members;

a temperature adjustment module to establish at least one temperature of the fluid of the fluid ejection device; and

an air bubble detect micro-electro-mechanical systems (ABD MEMS) pressure sensor to detect at least one impedance in the fluid corresponding to the at least one temperature, the ABD MEMS including a sensor plate.

5. The fluid ejection device according to claim 1, wherein the sensor plate is disposed in the channel.

6. The fluid ejection device according to claim 1, wherein the sensor unit comprises a pressure sensor unit such that the sensor plate is disposed in one of the ejection chambers.

7. A fluid ejection device, comprising:

a fluid supply chamber to store fluid;

a plurality of ejection chambers including nozzles and corresponding ejection members to selectively eject the fluid through the respective nozzles;

a channel to establish fluid communication between the fluid supply chamber and the ejection members;

a temperature adjustment module to establish at least one temperature of the fluid of the fluid ejection device; and

an air bubble detect micro-electro-mechanical systems (ABD MEMS) pressure sensor to detect at least one impedance in the fluid corresponding to the at least one temperature, the ABD MEMS including a sensor plate.

8. The fluid ejection device according to claim ~~16~~7, wherein the ABD MEMS selectively detects a first impedance of the fluid corresponding to a first temperature established by the temperature adjustment module and a second impedance of the fluid corresponding to a second temperature established by the temperature adjustment module different than the first temperature.

9. The fluid ejection device according to claim 7, wherein the ABD MEMS detects a plurality of impedances in the fluid corresponding to the at least one temperature at predetermine time periods.